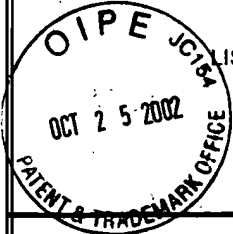
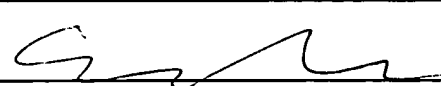


Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2042		SERIAL NO. 09/579,402		
 <p>LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)</p>				APPLICANT: Kei-Yu Ko				
				FILING DATE May 25, 2000		GROUP 2815		
U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
EL	AA	5,269,879	12/14/93	Rhoades et al.	156	643		
EL	AB	5,298,465	03/29/94	Levy	437	225		
EL	AC	5,658,425	08/19/97	Halman et al.	438	620		
EL	AD	5,685,914	11/11/97	Hills et al.	118	723		
EL	AE	5,780,338	07/14/98	Jeng et al.	438	253		
EL	AF	5,783,496	07/21/98	Flanner et al.	438	743		
EL	AG	5,817,579	10/06/98	Ko et al.	438	740		
EL	AH	5,830,807	11/03/98	Matsunaga et al.	438	714		
EL	AI	5,871,659	02/16/99	Sakano et al.	216	79		
EL	AJ	5,908,320	06/01/99	Chu et al.	437	743		
EL	AK	5,946,568	08/31/99	Hsiao et al.	438	253		
EL	AL	6,074,488	06/13/00	Roderick et al.	118	728		
FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
EL	AM	0 680 084 A1	28.04.95	EPO (Texas Instruments Inc.)				
EL	AN	WO 98/49719	05.11.98	WIPO (Micron Technology, Inc.)				
	AO							
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
EL	AP		Abatchev et al., <i>Study of the Boron-Phosphorous Doped and Undoped Silicate Glass Etching in</i>					
			CHF3/Ar Plasma, 96 ELECTROCHEM. SOC. PROCEEDINGS, No. 12, pp. 522-530 (1996).					
	AQ							
EXAMINER				DATE CONSIDERED				
				3/10/03				
<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>								

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				FILING DATE May 25, 2000	GROUP 2815		
U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
EL	AA	06/13/00	Tokunaga et al.	438	724	RECEIVED OCT 29 2002 TC 2800 MAIL ROOM	
EL	AB	09/12/00	Ko	438	706		
EL	AC	09/12/00	Ko et al.	438	723		
EL	AD	09/19/00	Ko et al.	257	644		
EL	AE	11/28/00	Xing et al.	438	396		
EL	AF	12/12/00	Yamada et al.	438	712		
EL	AG	12/26/00	Yaung et al.	438	592		
EL	AH	01/09/01	Xing et al.	438	706		
EL	AI	01/16/01	Hung et al.	216	67		
EL	AJ	02/06/01	Wang et al.	438	723		
EL	AK	07/03/01	Kondo	428	156		
EL	AL	01/08/02	Ko	438	714		
FOREIGN PATENT DOCUMENTS							
	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
	AM						
	AN						
	AO						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AP						
	AQ						
EXAMINER			DATE CONSIDERED				
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*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
a	AA	6,432,833 B1	08/13/02	Ko	438	714	
EL	AB	6,458,685 B1	10/01/02	Ko et al.	438	621	
EL	AC	09/532,088		Ko			03/21/2000
EL	AD	09/945,508		Ko			08/30/2001
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
FOREIGN PATENT DOCUMENTS							
	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
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	AN						
	AO						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AP						
	AQ						
EXAMINER				DATE CONSIDERED 3/10/03			
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				APPLICANT: Kei-Yu Ko			
				FILING DATE May 25, 2000		GROUP 2815	
U.S. PATENT DOCUMENTS							
*Examiner Initial	AA	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
EL	AA	5,883,436	03/16/99	Sadjadi et al.	257	760	
EL	AB	6,277,758 B1	08/21/01	Ko	438	706	
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
EL	AK	61-133555	12.03.84	Japan (NEC, Ltd.)			X
EL	AL	0 465 044 A2	19.06.91	EPO (AT&T)			
EL	AM	0 496 614 A1	23.01.92	EPO (NEC Corp.)			
EL	AN	0 763 850 A1	30.08.96	EPO (Applied Materials)			
	AO						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
EL	AP		W.G.M. van den Hoek et al., <i>Isotropic plasma etching of doped and undoped silicon dioxide for contact holes and vias</i> , 7 J. VAC. SCI. TECHNOL. A., No. 3, pp. 670-675 (May/June 1989).				
	AQ						
	AR						
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